

【NP-20】

Bottom-up Patterning Method by using of Microcontact Printing and Atomic Layer Deposition on Silicon

박미현, 장영진, 성명모
국민대학교 화학과

Self-assembled monolayers (SAMs) of alkylsiloxane were patterned by microcontact printing (μ CP) on SiO_2 , on scales from 0.5 to 100 μm . The patterned SAMs on SiO_2 define and direct the selective deposition of titanium oxide films using atomic layer deposition (ALD) with titanium isopropoxide and water as the precursor. The patterned SAMs and TiO_2 thin films have been investigated by atomic force microscopy (AFM).